## **Electronic Supplementary Information**

## Human Skin Interactive Self-powered Wearable Piezoelectric Bio-*e*-skin by Electrospun Poly-L-lactic Acid Nanofibers for Non-invasive Physiological Signal Monitoring

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Number	Wavenumber (cm <sup>-1</sup> )	Vibrational bands	
1	1756	ν(C=O)	
2	1453	$\delta_{as}(CH_3)$	
3	1383	$\delta_s(CH_3)$	
4	1360	δ(CH)	
5	1300	ν(C–H)	
6	1266	v(C–H)+ v(C–O–C)	
7	1209	$v_{as}(C-O-C)+r_{as}(CH_3)$	
8	1184	v <sub>as</sub> (C–O–C)	
9	1129	r <sub>s</sub> (CH <sub>3</sub> )	
10	1089	v <sub>s</sub> (C–O–C)	
11	1047	$v_{s}(C-CH_{3})$	

**Table S1.** Vibrational bands assignment of PLLA nanofibers based on FT-IR spectra



Figure S1. Height profile of AFM topographical image.

	Table S2. Comparison	of PBio-e-skin w	vith the previously	reported sensors
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Transduction	Active materials	Maximum	Lower Limit of	Pressure	Reference
mechanisms		sensitivity	detection	range	
Capacitance	PDMS/SWCNTs	2.3 x 10 <sup>-4</sup>	~50 Pa	< 1 MPa	[1]
		kPa <sup>-1</sup>			
Capacitance	Ecoflex	1.62 kPa <sup>-1</sup>		500 kPa	[2]
Capacitance	PDMS/SWCNTs	1.5 kPa <sup>-1</sup>	2.5 Pa	< 1 kPa	[3]
Capacitance/OF	PDMS	0.55 kPa <sup>-1</sup>	3 Pa	0.2 kPa	[4]
ET					
Capacitance/OF	PDPP3T	192 kPa <sup>-1</sup>	< 0.3 Pa	5 kPa	[5]
ET					
OFET/Piezoresi	Ge/Si NWs	11.5 kPa <sup>-1</sup>		15 kPa	[6]
stivity					
Piezoresistivity	rGO foam	15.2 kPa <sup>-1</sup>	163 Pa	49 kPa	[7]
Piezoresistivity	РРу	133.1 kPa <sup>-1</sup>	0.8 Pa	20 kPa	[8]
Piezoresistivity	PDMS	1.8 kPa <sup>-1</sup>	0.6 Pa	1.2 kPa	[9]
Piezoresistivity	PDMS/PtNWs	1.5 kPa <sup>-1</sup>	3 Pa	1.5 kPa	[10]
Piezoresistivity	SBS elastomer	10.7 MHz	13.3 Pa	13 kPa	[11]
		kPa <sup>-1</sup>			

Piezoresistivity/	AgNWs/PDMS/	204.4 kPa <sup>-1</sup>	0.2 Pa	4.5 kPa	[12]
Triboelectricity	CNT-PDMS				
Triboelectricity	PDMS/Ag NWs	0.31 kPa <sup>-1</sup>	2.1 Pa	10 kPa	[13]
Triboelectricity	micropyramid	0.29 VkPa <sup>-1</sup>	0.4 kPa		[14]
	structures PDMS				
	film				
Piezoelectricity	ZnOnanorod	2.1 µS kPa <sup>-1</sup>	3.5 kPa	31.5 kPa	[15]
Piezoelectricity	P(VDF-TrFE)	1.1 V kPa <sup>-1</sup>	0.1 Pa	2 kPa	[16]
	nanofiber				
Piezoelectricity	P(VDF-TrFE)	0.75 mV kPa <sup>-1</sup>		40 kPa	[17]
Piezoelectricity	P(VDF-TrFE)	458.2mV/N	0.1 N		[18]
	nanowires				
Piezoelectricity	P(VDF-TrFE)	269.4 mV/N	4 N		[19]
	microfiber array				
Piezoelectricity	P(VDF TrFF)/BaTiOa	257.9 mV/N	5 N		[20]
	nanocomposite				
	micropiliars				
Piezoelectricity	P(VDF-TrFE)/		0.1 MPa		[21]
Diama ala atminita	BrTiO <sub>3</sub> -FET	0.001 V/D-	20 D-		[22]
Plezoelectricity	P(VDF-	0.001 V/Pa	20 Pa		[22]
	TrFE)/BrTiO <sub>3</sub>				
	microstructured – FET				
Piezoelectricity	P(VDF-TrFE)/		2 MPa		[23]
	PbTiO <sub>3</sub> -FET				
Piezoelectricity	PVDF	1 kPa			[24]
Ferroelectret	Cellular PP/a-	0.1 V kPa <sup>-1</sup>	2 Pa	1 MPa	[25]
TFT	Si:H				
Piezoelectret	PDMS/PTFE	10 V kPa <sup>-1</sup>		50 kPa	[26]
Piezoelectret	PTFE/porous	1.5 V kPa <sup>-1</sup>		15 kPa	[27]
	PTFE				
Piezoelectricity	PLLA	0.003 V/Pa	18 Pa	0.3 MPa	This work
	nanofibers	(22 V/N)			

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